

Patent

OCT 20 2006

Customer No.: 31561  
Docket No.: 12009-US-PA-1  
Application No.: 10/605,782

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Applicant	: Shih-Chou Juan
Application No.	: 10/605,782
Filed	: 2003/10/27
For	: METHOD FOR FORMING NITRIDED TUNNEL OXIDE LAYER
Art Unit	: 2182
Examiner	: Mohsen, Ahmadi

Interview Request  
 002-1- 571-273-5062  
 002-1-571-273-8300  
 (Via fax: 5 pages)

Examiner Mohsen,

It is noted with great appreciation that the application can be in condition for allowance. In response thereto, please find the attached supplemental amendment.

I may be contacted through email at [Belinda@jcipgroup.com.tw](mailto:Belinda@jcipgroup.com.tw).

Respectfully Submitted,

Date: Oct. 20, 2006

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